

a floating pivot coupled to the lid and the actuator to align the lid with the opening when the lid closes.

28. (New) The system of claim 27, further comprising a fixed pivot coupled to the lid and the actuator.
29. (New) The system of claim 28, further comprising a guide link coupled to the fixed pivot.
30. (New) The system of claim 27, further comprising a load link coupled to the floating pivot.
31. (New) The system of claim 30, further comprising a guide shaft rotatably coupled to the load link.
32. (New) The system of claim 30, further comprising a drive pivot positioned at one end of the load link.
33. (New) The system of claim 32, further comprising a rod extending from the actuator coupled to the drive pivot to move the lid.
34. (New) The system of claim 27, further comprising a support bracket coupled to the actuator and the chamber body.
35. (New) A floating pivot to automatically align two objects, comprising:
  - a load link having first and second portions;

a bearing positioned between the first and second portions of the  
load link; and  
a self-centering spring coupled to the perimeter of the bearing.

36. (New) The pivot of claim 35, further comprising a tension shim positioned between the load link and the bearing.
37. (New) The pivot of claim 35, further comprising a pivot screw adapted to tighten the bearing.
38. (New) The pivot of claim 35, wherein the self-centering spring comprises an O-ring.
39. (New) The pivot of claim 35, further comprising a lid coupled to a first end of the load link.
40. (New) The pivot of claim 35, further comprising a chamber body coupled to a second end of the load link.
41. (New) The pivot of claim 35, wherein the self-centering spring allows radial movements or axial movements.
42. (New) The pivot of claim 35, wherein the self-centering spring allows self-centering of a lid to a chamber body.
43. (New) The pivot of claim 35, wherein the self-centering spring comprises coil springs.

44. (New) A semiconductor processing system, comprising:
- a chamber adapted to process a wafer, the chamber having an opening to facilitate access to the interior of the chamber; and
  - a lid coupled to the chamber opening, the lid having an open position and a closed position, the open and closed positions being moved horizontally in a substantially parallel manner relative to the opening; and
  - an actuator coupled to the lid to move the lid between the closed position and the open position.
45. (New) The system of claim 44, further comprising a floating pivot to automatically align the lid to the body of the chamber.
46. (New) The system of claim 45, wherein the pivot further comprises:
- a load link having first and second portions;
  - a bearing positioned between the first and second portions of the bearing; and
  - a self-centering spring coupled to the perimeter of the bearing.